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1. (Currently Amended) A method for determining the wettability of a particulate surface comprising:

inserting a test device having the particulate surface into a test liquid to form a liquid meniscus;

measuring the liquid meniscus to generate a liquid meniscus measurement; and calculating the wettability of the particulate surface using the liquid meniscus measurement;

wherein the test device has a cylindrical or a partially cylindrical surface.

2. (Original) The method of Claim 1, wherein the step of measuring the liquid meniscus is performed using an optical measuring device.

3. (Original) The method of Claim 1, wherein the liquid meniscus measurement is a height of the liquid meniscus.

4. (Original) The method of Claim 1, wherein the liquid meniscus measurement is an external meniscus profile.

5. (Original) The method of Claim 1, wherein the test device comprises:
a substrate having a surface area;
a layer of adhesive material applied to at least a portion of the surface area of the substrate; and
a layer of particulate material attached to the adhesive material to form the particulate surface of the test device.

6. (Currently Amended) A system for determining the wettability of particulate surface comprising:

a test device having the particulate surface;
a test liquid; and

{WP233392;1}

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a measurement device;

wherein the test device has a cylindrical or a partially cylindrical surface.

7. (Original) The system of Claim 6, wherein the measurement device is an optical measuring device.

8. (Original) The system of Claim 6, wherein the test device comprises:

a substrate having a surface area;

a layer of adhesive material applied to at least a portion of the surface area of the substrate; and

a layer of particulate material attached to the adhesive material to form the particulate surface of the test device.

9. (New) A method for determining the wettability of a particulate surface comprising:

inserting a test device having the particulate surface into a test liquid to form a liquid meniscus;
measuring the liquid meniscus to generate a liquid meniscus measurement; and
calculating the wettability of the particulate surface using the liquid meniscus measurement;

wherein the test device comprises:

a substrate having a surface area;

a layer of adhesive material applied to at least a portion of the surface area of the substrate; and

a layer of particulate material attached to the adhesive material to form the particulate surface of the test device.

10. (New) The method of Claim 9, wherein the step of measuring the liquid meniscus is performed using an optical measuring device.

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11. (New) The method of Claim 9, wherein the liquid meniscus measurement is a height of the liquid meniscus.

12. (New) The method of Claim 9, wherein the liquid meniscus measurement is an external meniscus profile.

13. (New) A system for determining the wettability of particulate surface comprising:

a test device having the particulate surface;

a test liquid; and

a measurement device;

wherein the test device comprises:

a substrate having a surface area;

a layer of adhesive material applied to at least a portion of the surface area of the substrate; and

a layer of particulate material attached to the adhesive material to form the particulate surface of the test device.

14. (New) The system of Claim 13, wherein the measurement device is an optical measuring device.